非極性 air/AlGaN DBR 垂直微小共振器の作製と評価 Fabrication and characterization of nonpolar nitride air-gap DBR vertical microcavities

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Semiconductor distributed Bragg reflector (DBR) microcavities (MCs) have been widely used for optoelectronics. In III-Nitrides, the difficulty in obtaining a high index contrast means that an air-gap nitride DBR MC turns out to be a promising option [1]. However, due to the chemical inertness and poor selectivity between various nitride materials, no complete air/nitride DBR MCs have been reported to date. In this work, we report the successful fabrication of complete air-gap DBR MCs using a thermal decomposition process [2]. We observe quality factors as high as 1600.

The samples were grown on m-plane free-standing GaN substrates. After the deposition of 4 periods of AlGaN/GaN(117nm/296nm) layers, a AlGaN cavity with single InGaN quantum well (QW) at the center was grown, which was then followed by another 3 GaN/AlGaN(296nm/117nm) layers. Patterns were created in the structure using electron beam lithography and chlorine dry etching. The GaN around the openings was then decomposed by annealing for 20~30mins in the MOCVD reactor at 1070°C, while the AlGaN layers remained unaffected. This process resulted in the formation of air/AlGaN DBR MCs with single InGaN QW at the cavity center (Inset in Fig.2). Four samples have been grown, with cavity thickness ranging from 152 nm to 159nm.

 μ PL measurements were performed on the samples at room temperature using a CW 266nm laser. A systematic shift of the cavity mode with increasing cavity thickness was observed (Fig. 1). By fitting of a Lorentzian profile, the Q factor of one mode is estimated to be 1600 (Fig. 2). Each spectrum exhibits two modes, which originate from the anisotropic in-plane properties of the nonpolar sample, with E || a(X) and E || c(Z), respectively. The energy difference of the modes is due to a difference in refractive index (Δn = n_e - n_o ~0.02). The intensity of the mode with E || a is much higher than that with E || c. With a k · p Hamiltonian [3], the matrix elements between the first conduction band and first valence band were calculated for our QW. It is found that near the Γ point, the matrix element $|M_X|^2$ is much larger than $|M_Z|^2$, which is consistent with our experimental observations.

In summary, nitride air-gap DBR MCs have been successfully fabricated using the thermal decomposition of GaN. A Q factor of 1600 reveals the high quality of the cavities, and the mode positions can be fine-tuned by varying the cavity thickness. These results show that air-gap DBR MCs fabricated by thermal decomposition of GaN are very promising for research on light-matter interactions in nitrides.





Fig. 1 Systematic shift of cavity mode with increasing cavity thickness (~152nm-~159nm).



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